

PTO/SB/08a (08-03)

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet

1

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Attorney Docket Number

071469-0304673

U. S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				
RMS	A	JP 09-148322	06-06-1997	IZAWA		

Examiner Signature	/Kelly Stouffer/	Date Considered	02/06/2007
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Substitute for form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)		Complete if Known			
		Application Number	10/644,958		
		Filing Date	08/21/2003		
		First Named Inventor	NORIAKI FUKIAGE		
		Art Unit	1762		
		Examiner Name			
Sheet	1	of	1	Attorney Docket Number	071469-0304673

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
KMS	I	KUDOH ET AL., "Directional Plasma CVD Technology for Sub-Quarter Micrometer Feature Size Multilevel Interconnection," 1997 International Conference on Solid State Devices and Materials, Japan Society of Applied Physics (Hamamatsu), p. 290-291, (Sept. 1997).	
KMS	II	ANDOSCA, R.G. ET AL., "Silicon dioxide films deposited by electron cyclotron resonance plasma enhanced chemical vapor deposition," Journal of Applied Physics, Vol. 72 (No. 3), p. 1126-1132, (August 1, 1992).	

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